

<b>Notice of References Cited</b>	Application/Control No. 10/590,918	Applicant(s)/Patent Under Reexamination ZOU ET AL.
	Examiner Monique R. Jackson	Art Unit 1787

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,066,581	05-2000	Chivukula et al.	501/12
*	B	US-6,247,799	06-2001	Sakamaki et al.	347/68
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Zhang et al, Self-buffered BaxSr <sub>1-x</sub> TiO <sub>3</sub> films by sol-gel and RF magnetron sputtering method, Materials Research Bulletin 38, 2003, p133-139.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.